

Supporting Information

Role of gallium and yttrium dopants on the stability and performance of solution processed indium oxide thin-film transistors

Felix Jaehnike,^{†,‡} Duy Vu Pham,[†] Claudia Bock[§] and Ulrich Kunze[‡]

[†]Evonik Industries AG, 45772 Marl, Germany.

[‡] Werkstoffe und Nanoelektronik, Ruhr-Universität Bochum, 44801 Bochum, Germany.

[§] Mikrosystemtechnik, Ruhr-Universität Bochum, 44801 Bochum, Germany

Corresponding Author

E-Mail: claudia.bock@rub.de

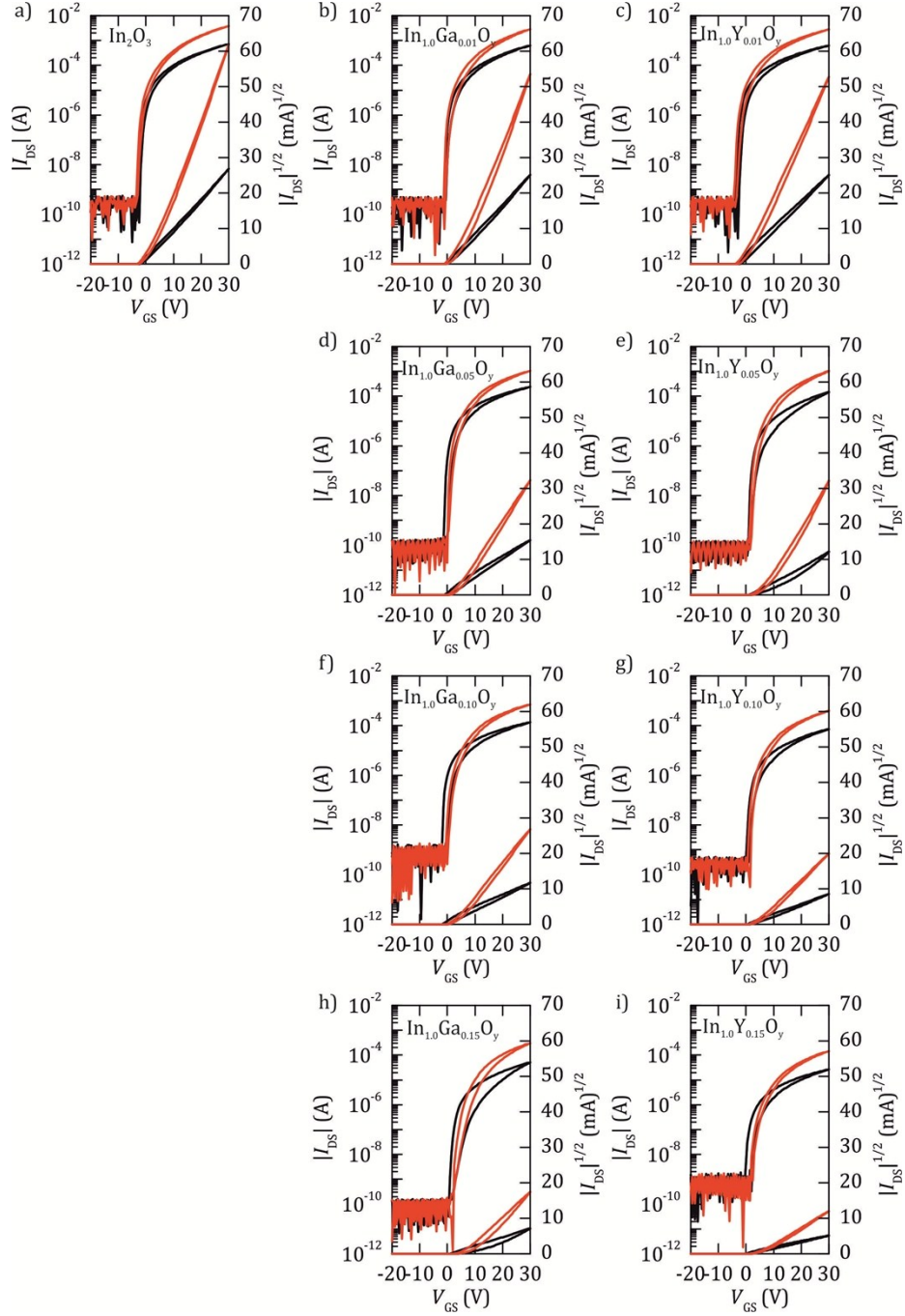


Fig. S 1: Transfer characteristics of TFTs with different metal-oxides as semiconductor material: In_2O_3 (first column), InGaO (second column) and InYO (third column) in the proportions b, c) 100:1, d, e) 100:5, f, g) 100:10 and h, i) 100:15. Black curves: $V_{\text{DS}} = 2 \text{ V}$, red curves: $V_{\text{DS}} = 10 \text{ V}$.

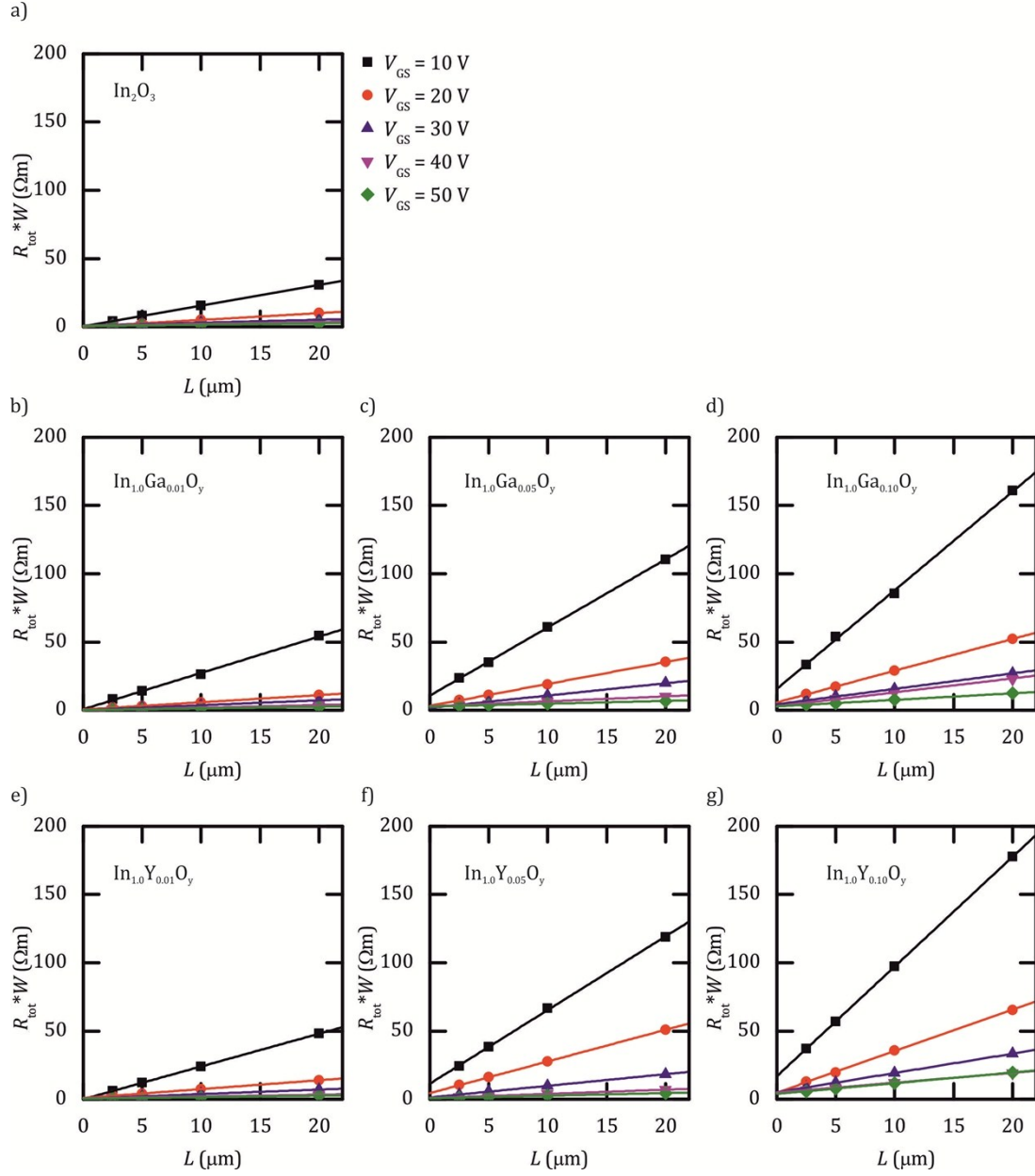


Fig. S2: Width-normalized device resistance $R_{\text{tot}} * W$ as a function of channel length L ($10\text{ V} \leq V_{\text{GS}} \leq 50\text{ V}$) for transistors with (a) undoped In_2O_3 , (b-d) $\text{In}_{1.0}\text{Ga}_x\text{O}_y$ with $x = 0.01; 0.05; 0.1$ and (e-g) $\text{In}_{1.0}\text{Y}_x\text{O}_y$ with $x = 0.01; 0.05; 0.1$.

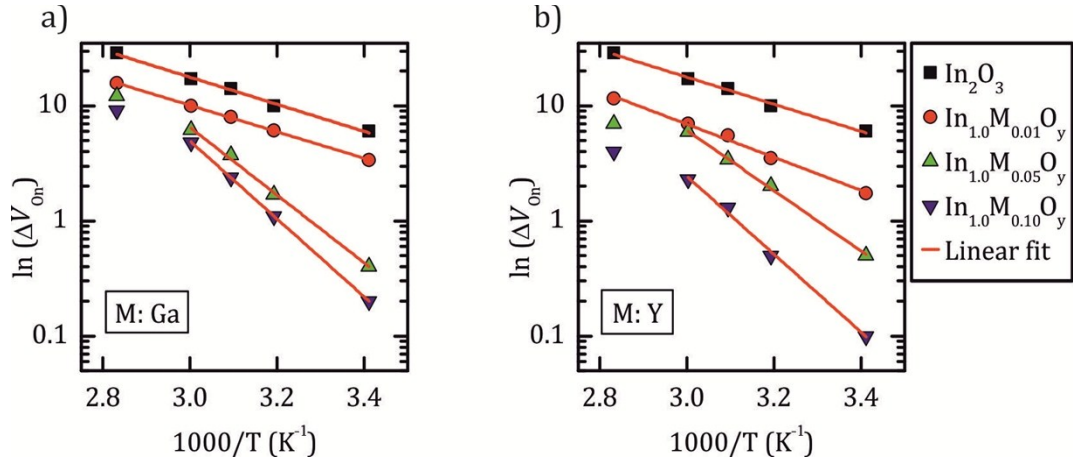


Fig. S 3: Semi-logarithmic scale of the onset voltage shift ΔV_{on} during temperature stress versus the reciprocal temperature of TFTs with different metal oxide compositions: a) indium oxide and $In_{1.0}Ga_xO_y$ and b) Indium oxide und $In_{1.0}Y_xO_y$ with $x = 0.01, 0.05, 0.10$. The red curves are the linear fits of the data points.